



Session Title:	[ThF2] Nano Thin Film Deposition VII
Session Date:	November 14 (Thu.), 2024
Session Time:	10:50-12:20
Session Room:	Room F (Ballroom, 5F, Grand Josun Busan)
Session Chair:	Prof. Woo-Jae Lee (Pukyong Nat'l Univ., Korea)

[ThF2-1] [Invited]

10:50-11:15

Precursor Chemistry in Semiconductor Industry

Jin Sik Kim, Myeong-Ho Kim, Byung-Kwan Kim, Yun-Gyeong Yi, Yoon-A Park, Da-Som-Yu, Seung-Gyun Hong, and Su-Jung-Lee (UP Chemical, Korea)

[ThF2-2] [Invited]

11:15-11:40

Computational Fluid Dynamics Analysis of Canisters for Mass Delivery of Solid Precursors

Seung-Ho Seo, Jong-Ean Park, Hee-Jun Lee, Yeongjong Lee, and Deahyun Kim (GO Element Co., Ltd., Korea)

[ThF2-2]

11:40-12:00

Dielectrics with Sub-Surface Dopant Implantation-Mediated Lattice Relaxation and VO Annihilation via Chemo-Physical Plasma Annealing

Gyuha Lee (POSTECH, Korea), Geongu Han (Seoul Nat'l Univ., Korea), Hyongjune Kim, Sangwon Lee, Jeongmin Oh, and Jihwan An (POSTECH, Korea)

[ThF2-4]

12:00-12:20

Effect of Oxygen Binding Energy of Hf, Ga and Al on Amorphous Zn-Sn-O Thin Film Transistor

Sunjin Lee, Heyon Dong Kim, Tae Ho Kim, Sang Ji Kim, and Sang Yeol Lee (Gachon Univ., and Gachon Advanced Inst. of Semiconductor Tech., Korea)